IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT(S): Dong-Su Kim

SERIAL NO.: 09/899,784

EXAMINER: Fernando L. Toledo

DATE FILED: July 5, 2001

ART UNIT: 2823

FOR: METHOD OF FABRICATING SILICA MICROSTRUCTURES

## CERTIFICATE OF MAILING UNDER 37 CFR §1.8

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to the ASSISTANT COMMISSIONER FOR PATENTS, WASHINGTON, DC 20231 on January 7, 2003.

Steve Cha, Reg. No. 44,069

(Name of depositor)

**Assistant Commissioner for Patents** Washington, D.C. 20231

Sir:

## INFORMATION DISCLOSURE STATEMENT

In accordance with Applicant's and Applicant's representatives' Duty of Disclosure under 37 CFR § 1.56, and pursuant to 37 CFR §1.97 and MPEP 717.05(b), Applicant(s) submit herewith documentary information for consideration by the Examiner. Information herein cited is only set forth in fulfillment of Applicant's duty of candor in disclosing all information brought to his attention, and is not an admission that it can be used adversely. The publications forwarded herewith are listed on the enclosed Form PTO-1449. Applicant(s) request that the Examiner, upon reviewing the enclosed materials, initial the enclosed form and return a copy thereof in accordance with the instructions on the form.

Enclosed please find copies of seven foreign patent listed on the attached Form PTO-1449. A check in the amount of \$180.00 is enclosed to cover the cost for submission of the Information Please charge any additional fees or credit any overpayment to the Disclosure Statement. undersigned firm's Deposit Account No. 502-470.

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Respectfully submitte

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Date: January 7, 2003

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